

A. Specifications (세부사항)

Scanning area

No	Objective Lens	F.O.V
1	2.5x Interference lens	2.49 x 1.87mm
2	5x Interference lens	1.28 x 0.96mm
3	10x Interference lens	0.64 x 0.48mm
4	20X Interference lens	0.32 x 0.24mm
5	50X Interference lens	0.13 x 0.096mm

Scanning Method

16bit LVDT Sensor Closed-Loop Controlled PZT Scanning

Scanning Range(height)

Z-axis : 270um

Scanning Speed

High Accuracy Mode : 2.4 μ m/sec(x1~x5 user-selectable)

Resolution (Z Axis)

WSI < 0.5 nm

PSI < 0.1 nm

Step Height Repeatability

$\leq 0.1\%$ @ 1σ (VLSI 7.969um ± 0.065 시편 기준, 16회 반복)

System Configuration

Manual Probe Tip/Tilt : $\pm 6^\circ$

Manual Coarse Z axis Stage : 100mm

Motorized XY Stage : 100mm x 100mm

Manual lenses Turret

White-light LED Illumination

Main Controller

Stitching Function (Part 300)

B. Operating Station

Computer System

The latest Dell Compaq computer.

1TB HDD , DVD-RW , Windows 7

Monitors

23" Color LCD Monitor

C. Software

NanoView / NanoMap

D. Measuring Method

Measuring method

White Light Scanning Interferometry

Phase Shift Interferometry

E. Training and Warranty

Installation & Training for 3 days at customer's facility

Warranty for 12 months after installation

Installation by NanoSystem CO., LTD.

F. Dimension and Weight

Machine Dimension

350(W) x 500(D) x 650(H) mm

System Weight

65kg

Max. Workpiece

< 3kg

G. Environmental Conditions

Room Air Humidity

< 60%

Environmental Temperature

20 °C ±2.0 °C

Electric Power

220V±5%, 50-60Hz, Single-phase

Air Pressure

> 5Kgf/cm²